

**Semiconductor devices - Micro-electromechanical  
devices - Part 21: Test method for Poisson's ratio of thin  
film MEMS materials**

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## EESTI STANDARDI EESSÕNA

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ICS 31.080

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English Version

Semiconductor devices - Micro-electromechanical devices -  
Part 21: Test method for Poisson's ratio of thin film MEMS  
materials  
(IEC 62047-21:2014)

Dispositifs à semiconducteurs - Dispositifs  
microélectromécaniques -  
Partie 21: Méthode d'essai relative au coefficient de  
Poisson des matériaux MEMS en couche mince  
(CEI 62047-21:2014)

Halbleiterbauelemente - Bauelemente der  
Mikrosystemtechnik -  
Teil 21: Prüfverfahren zur Querkontraktionszahl von  
Dünnschichtwerkstoffen der Mikrosystemtechnik  
(IEC 62047-21:2014)

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Comité Européen de Normalisation Electrotechnique  
Europäisches Komitee für Elektrotechnische Normung

CEN-CENELEC Management Centre: Avenue Marnix 17, B-1000 Brussels

## Foreword

The text of document 47F/185/FDIS, future edition 1 of IEC 62047-21, prepared by SC 47F "Microelectromechanical systems" of IEC/TC 47 "Semiconductor devices" was submitted to the IEC-CENELEC parallel vote and approved by CENELEC as EN 62047-21:2014.

The following dates are fixed:

- latest date by which the document has to be implemented at national level by publication of an identical national standard or by endorsement (dop) 2015-04-24
- latest date by which the national standards conflicting with the document have to be withdrawn (dow) 2017-07-24

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**Annex ZA**  
(normative)

**Normative references to international publications  
with their corresponding European publications**

The following documents, in whole or in part, are normatively referenced in this document and are indispensable for its application. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

NOTE 1 When an International Publication has been modified by common modifications, indicated by (mod), the relevant EN/HD applies.

NOTE 2 Up-to-date information on the latest versions of the European Standards listed in this annex is available here: [www.cenelec.eu](http://www.cenelec.eu)

<u>Publication</u>	<u>Year</u>	<u>Title</u>	<u>EN/HD</u>	<u>Year</u>
IEC 62047-8	2011	Semiconductor devices - Micro-electromechanical devices - Part 8: Strip bending test method for tensile property measurement of thin films	EN 62047-8	2011
ASTM E132-04	2010	Standard test method for Poisson's ratio at room temperature	-	-

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## CONTENTS

FOREWORD.....	3
1 Scope.....	5
2 Normative references .....	5
3 Terms, definitions, symbols and designations .....	5
3.1 Terms and definitions.....	5
3.2 Symbols and designations .....	5
4 Test piece .....	6
4.1 General.....	6
4.2 Shape of the test piece .....	7
4.3 Measurement of dimensions .....	7
5 Testing method and test apparatus.....	7
5.1 Test principle .....	7
5.2 Test machine .....	7
5.3 Test procedure.....	7
5.3.1 Test procedure for type 1 test piece.....	7
5.3.2 Test procedure for type 2 test piece.....	8
5.4 Test environment .....	8
6 Test report.....	8
Annex A (informative) Measurement example of Poisson's ratio using type 1 test piece.....	9
A.1 Fabrication of the test piece .....	9
A.2 Dimensions of the test piece .....	9
A.3 Test procedures .....	9
A.4 Test results.....	10
Annex B (informative) Analysis of test results obtained from a type 2 test piece.....	11
B.1 General.....	11
B.2 Evaluation of stress and strain in circular and rectangular membranes .....	11
B.3 Evaluation of Poisson's ratio .....	12
Bibliography.....	13
Figure 1 – Two types of test pieces for the measurement of Poisson's ratio .....	6
Figure A.1 – Optical images of markers for strain measurement by DIC.....	9
Figure A.2 – Graphs of load and strain in the longitudinal and transverse directions .....	10
Table 1 – Symbols and designations of a test piece.....	6